PROCESS FOR SYNTHESIZING A THIN FILM OR COMPOSITION LAYER VIA NON-CONTACT PRESSURE CONTAINMENT

Abstract of the Disclosure

A process for synthesizing a thin film or composition layer from a plurality of precursor layers supported on a substrate, includes exposing the plurality of precursor layers to non-contact pressure, and heating the plurality of precursor layers under the non-contact pressure to a reaction temperature sufficient to promote the formation of the film or composition layer.